IN THE CLAIMS

- 1. (Currently Amended) A semiconductor processing chamber comprising:
 - a chamber body having an aperture formed in a bottom of the chamber body;
 - a substrate support disposed in the chamber body;
- a moveable shaft coupled to the substrate support, the movable shaft extending through the aperture;
 - a step formed in an inner surface of the aperture; and
- a substantially annular guard ring positioned within the step, the guard ring having a portion that slopes radially inward and upwards into sealing contact with the shaft, wherein the guard ring further comprises:
- a base portion having an outer circumference and an inner perimeter, wherein the outer circumference contacts the step and the inner perimeter is adapted for substantially sealing a gap between the shaft and the aperture; and

wherein the inner perimeter is formed substantially as a wedge.

- 2. (Previously Presented) The chamber of claim 1, wherein the step further comprises:
 - a lip formed in the step adapted to retain the guard ring within the step.
- 3. (Cancelled)
- 4. (Currently Amended) The chamber of claim 3 claim 1, wherein the outer circumference is formed as a substantially right angle to a bottom surface of the step.
- 5. (Currently Amended) The chamber of claim 3 claim 1, wherein the outer circumference flares outward toward the substrate support.
- 6. (Cancelled)

- 7. (Currently Amended) The chamber of claim 6 claim 1, wherein a surface of the wedge slopes upward to project above the bottom of the chamber body.
- 8. (Withdrawn, Currently Amended) The chamber of claim 1, wherein the guard ring further comprises:
 - a first flange coupled to the base portion and disposed against the shaft;
- a second flange <u>coupled to the base portion and</u> disposed against the step formed in the inner surface;
 - a base portion coupling the first and second flanges; and
 - a channel separating the first flange from the second flange.
- 9. (Withdrawn) The chamber of claim 8, wherein the second flange forms a substantially ninety-degree angle with the base portion.
- 10. (Cancelled)
- 11. (Withdrawn) The chamber of claim 8, wherein at least a portion of an inner surface of the second flange comprises a recess for engaging a lip formed on the step.
- 12. (Withdrawn) The chamber of claim 8, wherein the first flange extends radially inward from the base portion.
- 13. (Withdrawn) The chamber of claim 12, wherein the first flange is adapted to be compressed radially outward.
- 14. (Withdrawn) The chamber of claim 8, wherein a first end of the first flange comprises a tapered tip, the first end being disposed distal from the base portion.
- 15. (Withdrawn) The chamber of claim 8, wherein the channel is wide enough to substantially prevent contact between the first and second flanges.

- 16. (Withdrawn) The chamber of claim 8, wherein the guard ring is formed as a closed, continuous ring.
- 17. (Withdrawn) The chamber of claim 8, wherein the ring is formed as a split ring adapted for closing upon compression of the guard ring.
- 18. (Withdrawn) The chamber of claim 8, wherein a portion of the inner perimeter of the ring is formed substantially parallel to a diameter of the ring.
- 19. (Withdrawn) The chamber of claim 8, wherein the ring is formed as a two-component ring comprising:
 - a first, substantially C-shaped component; and
 - a second, substantially wedge-shaped component comprising:
 - an arcuate outer portion having a radius conforming to the radius of the outer circumference of the ring; and
 - a flat inner portion substantially parallel to a diameter of the ring,
- wherein the first component and the second component are adapted to be fit together to form the ring.
- 20. (Withdrawn) The chamber of claim 8, further comprising an insert positioned within a portion of the inner perimeter, the insert comprising:
 - an arced surface conforming to the inner perimeter of the ring; and a flat surface be positioned substantially parallel to a diameter of the ring.
- 21. (Cancelled)